

FIG. 1

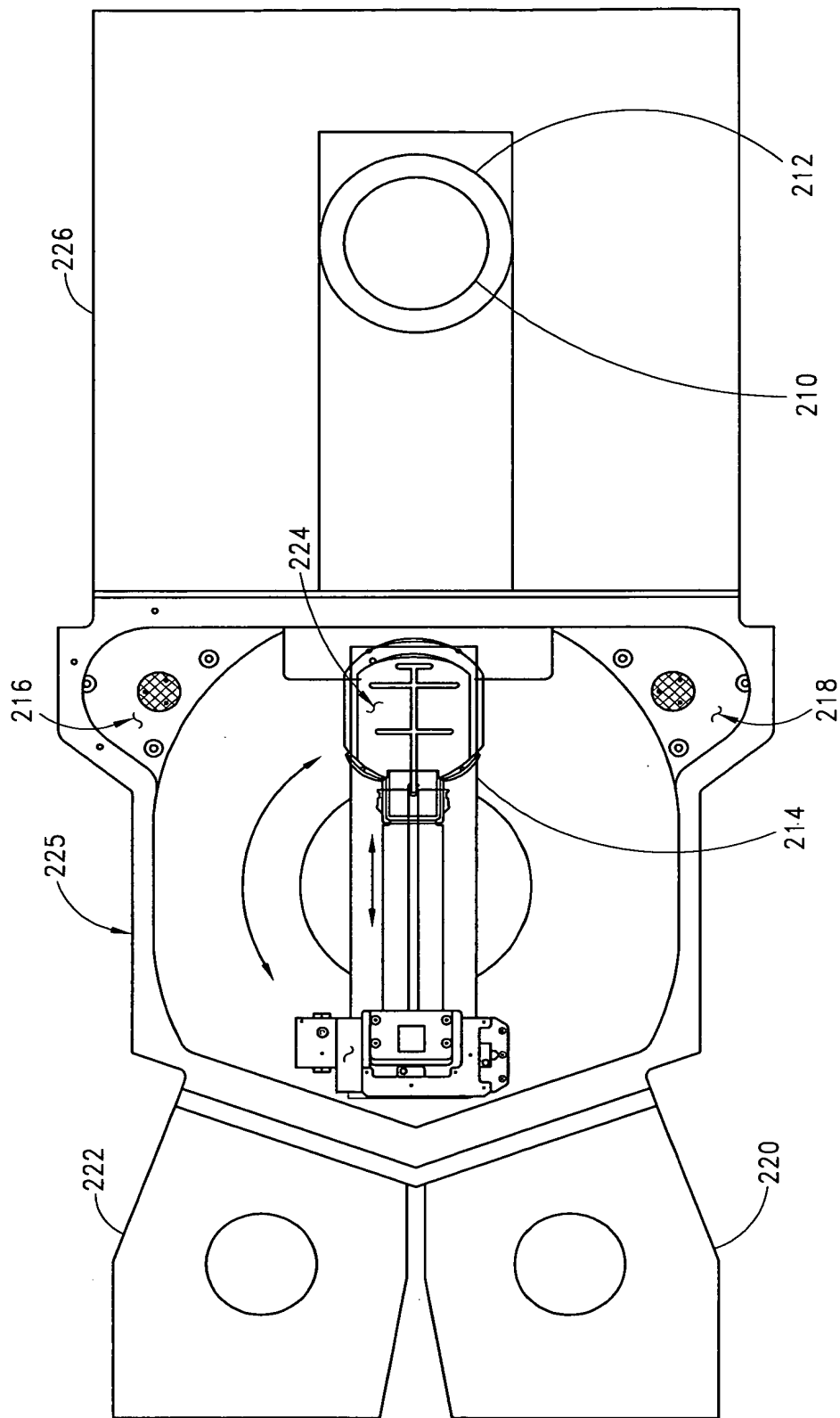


FIG. 2A

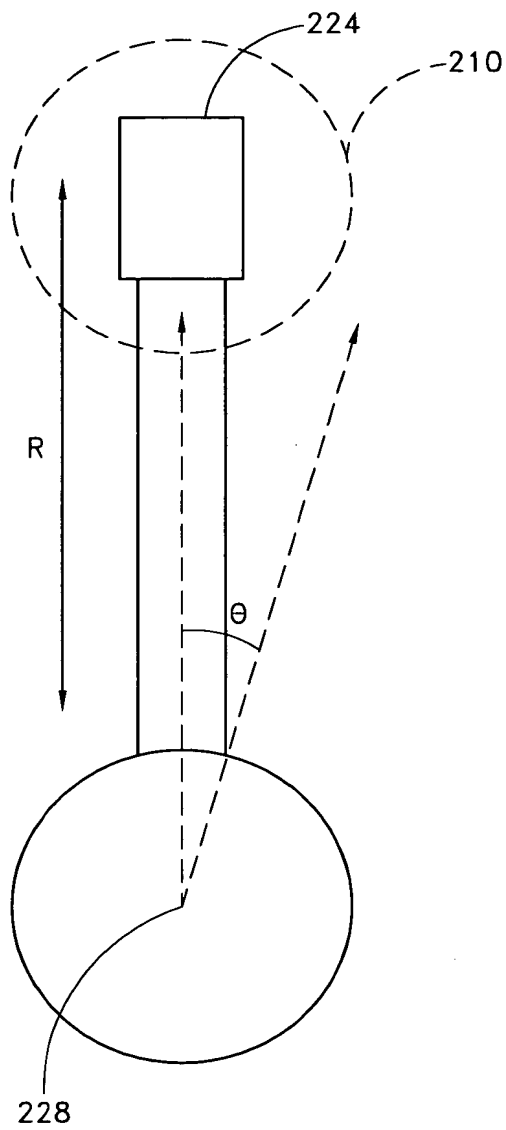


FIG. 2B

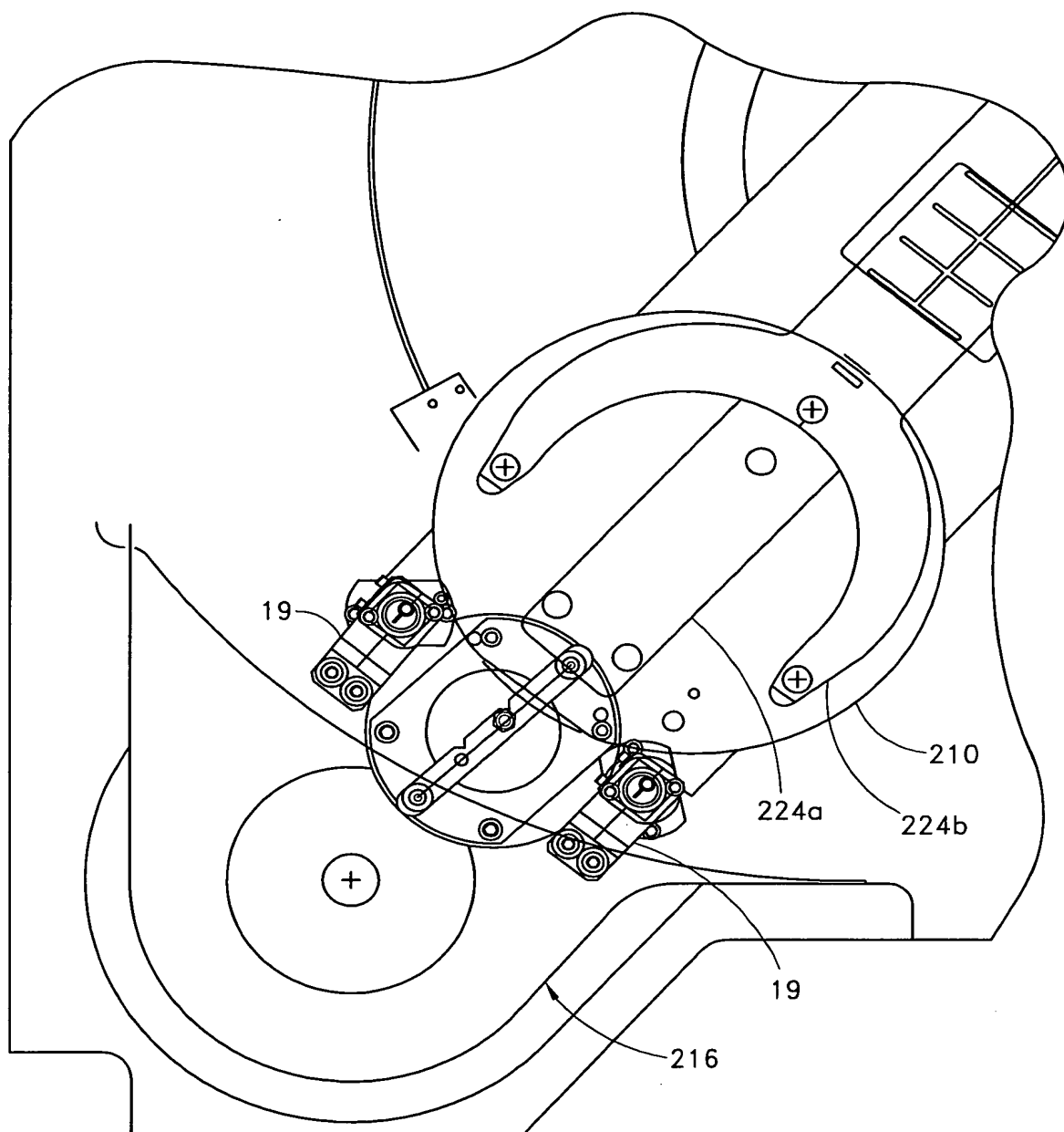


FIG. 2C

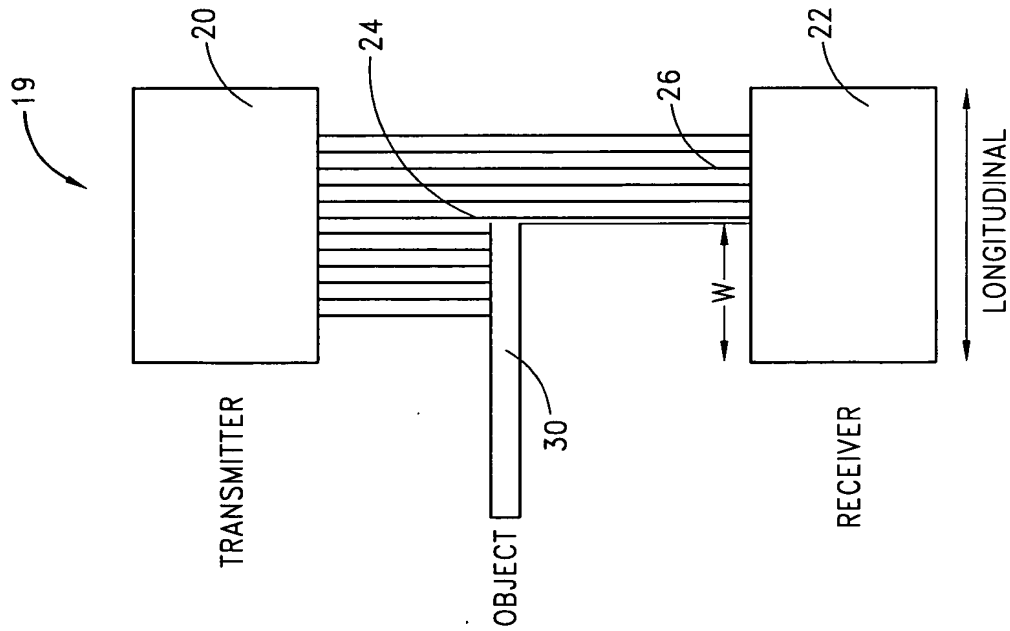


FIG. 4

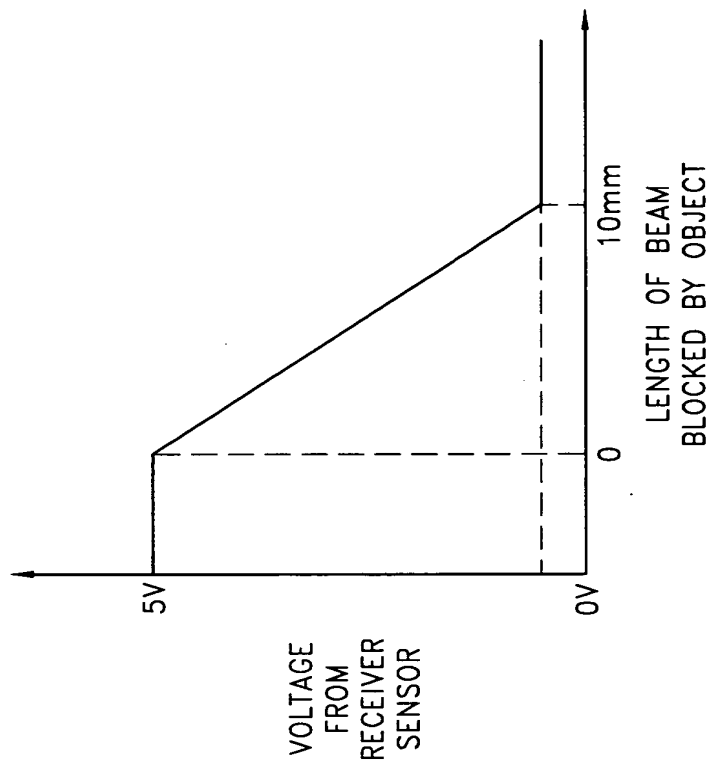


FIG. 5

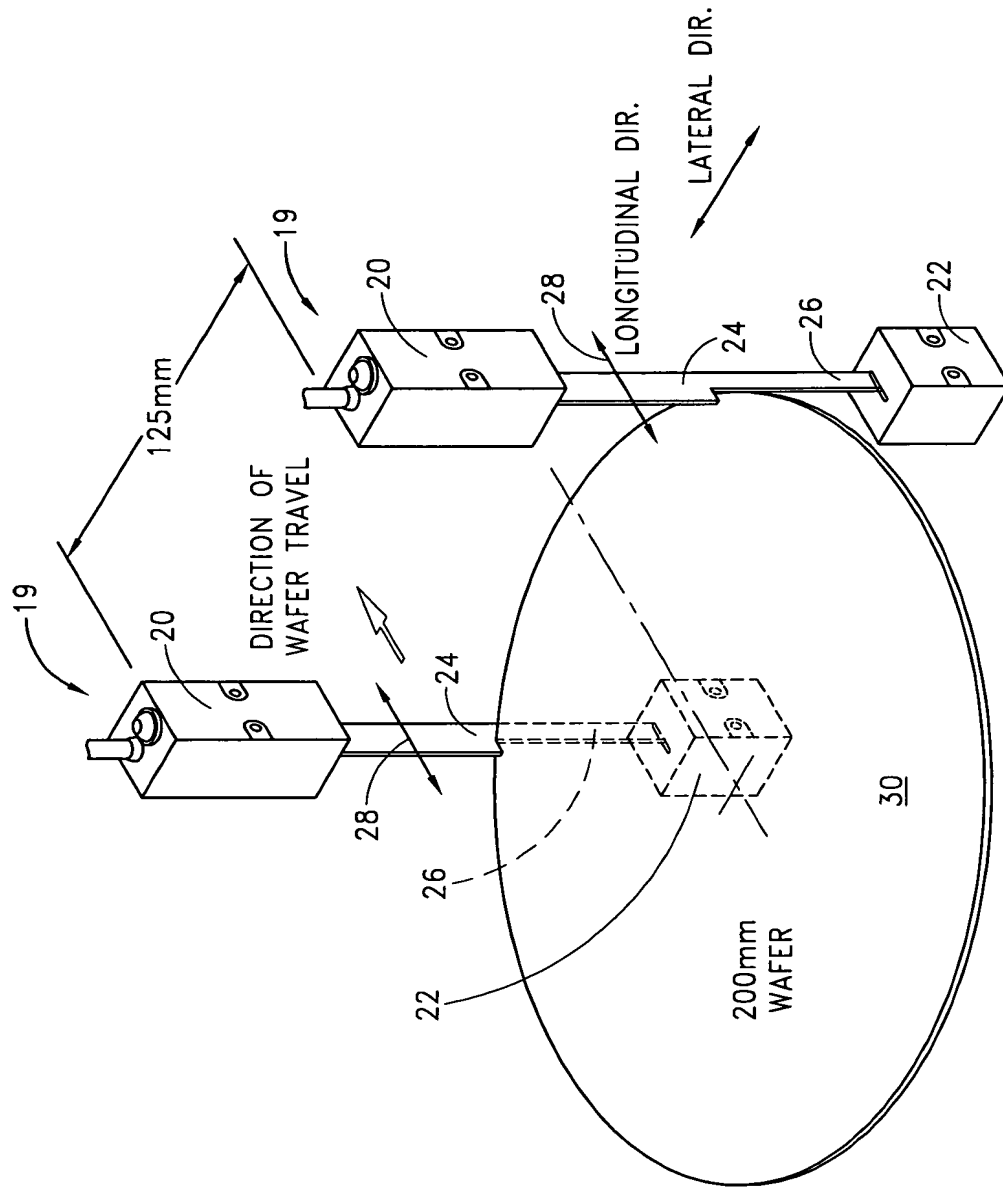


FIG. 6

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graph TD
    400[400 REFERENCE WAFER MANUALLY  
PLACED AT CENTER OF SUSCEPTOR] --> 410[410 REFERENCE WAFER MOVED TO  
CENTERING STATION, COOL-DOWN  
STATIONS AND LOAD-LOCK CASSETTES  
TO ESTABLISH NOMINAL POSITIONS]
    410 --> 420[420 ALIGN SENSORS AT CENTERING  
STATION TO BE PARALLEL TO TRANSLATION  
AXIS AT CENTERING STATION]
    420 --> 430[430 DEFINE NOMINAL CENTERING POSITION  
AS A POSITION WHERE REFERENCE  
WAFER FRONT OR REAR EDGE PARTIALLY  
INTERCEPTS BOTH SENSORS]
    430 --> 440[440 DETERMINE POSITION g OF  
REFERENCE WAFER AT NOMINAL  
CENTERING POSITION]

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FIG. 7

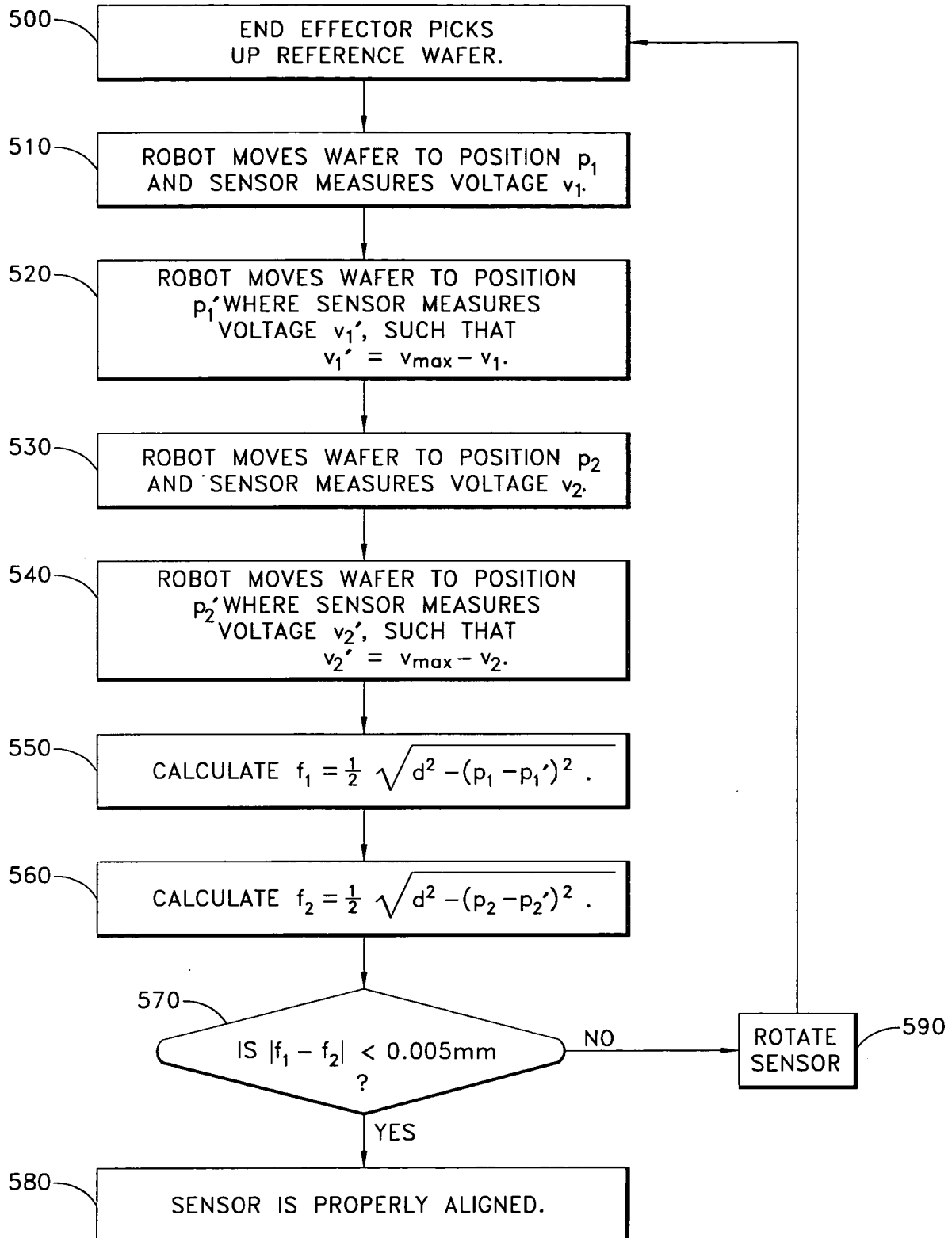


FIG. 8

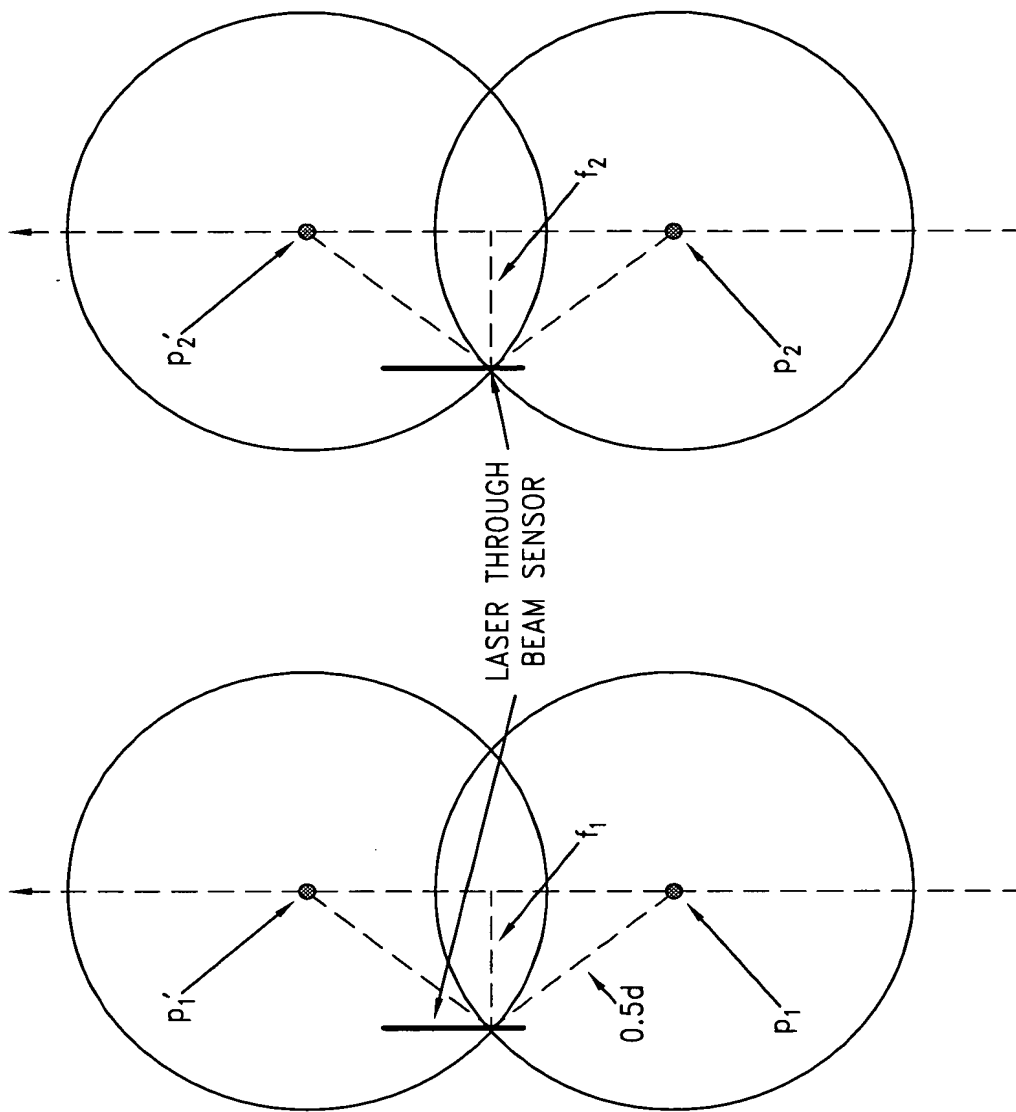


FIG. 9

FIG. 10

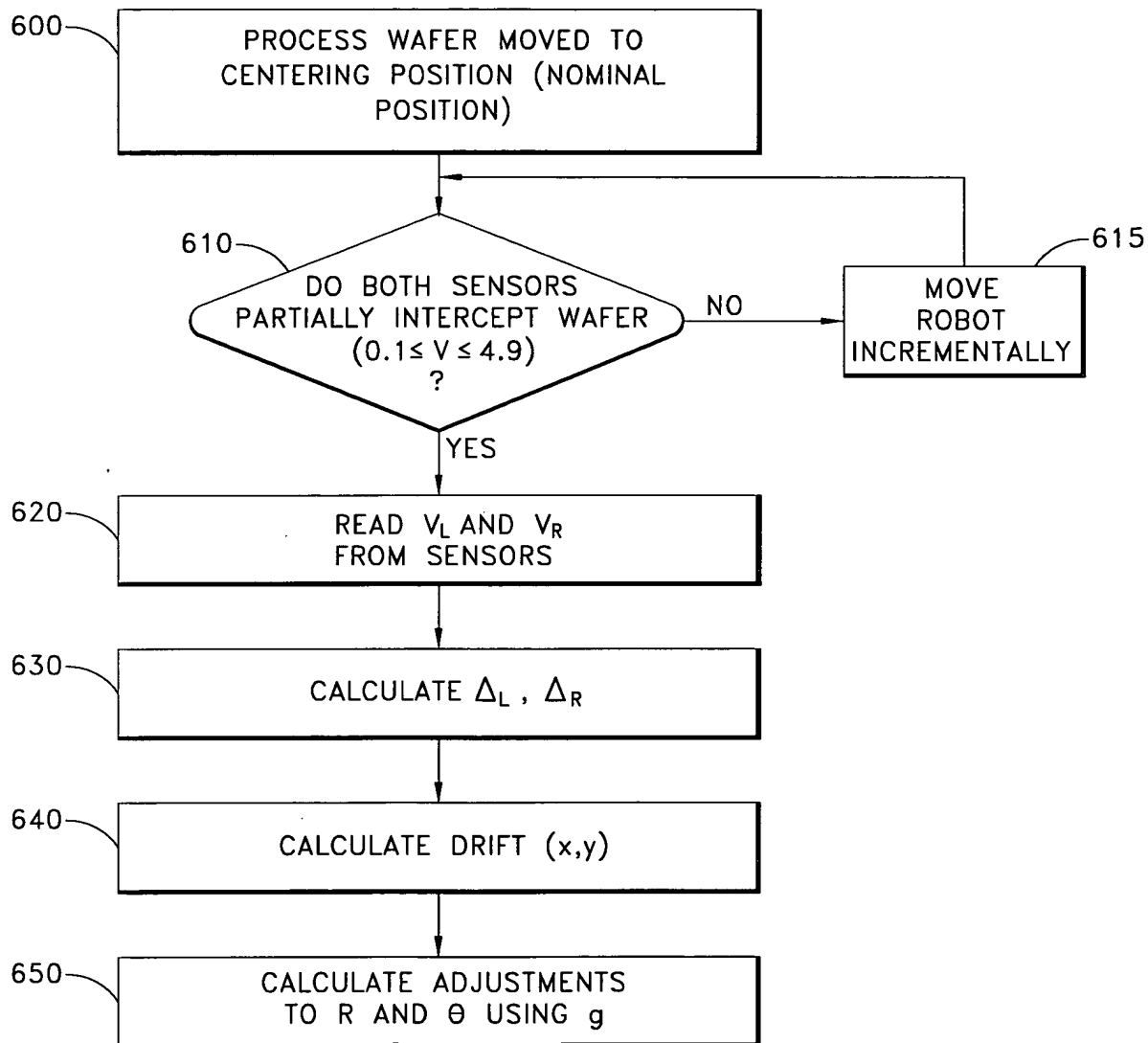


FIG. 11

WAFER POSITION/ERROR CALCULATION

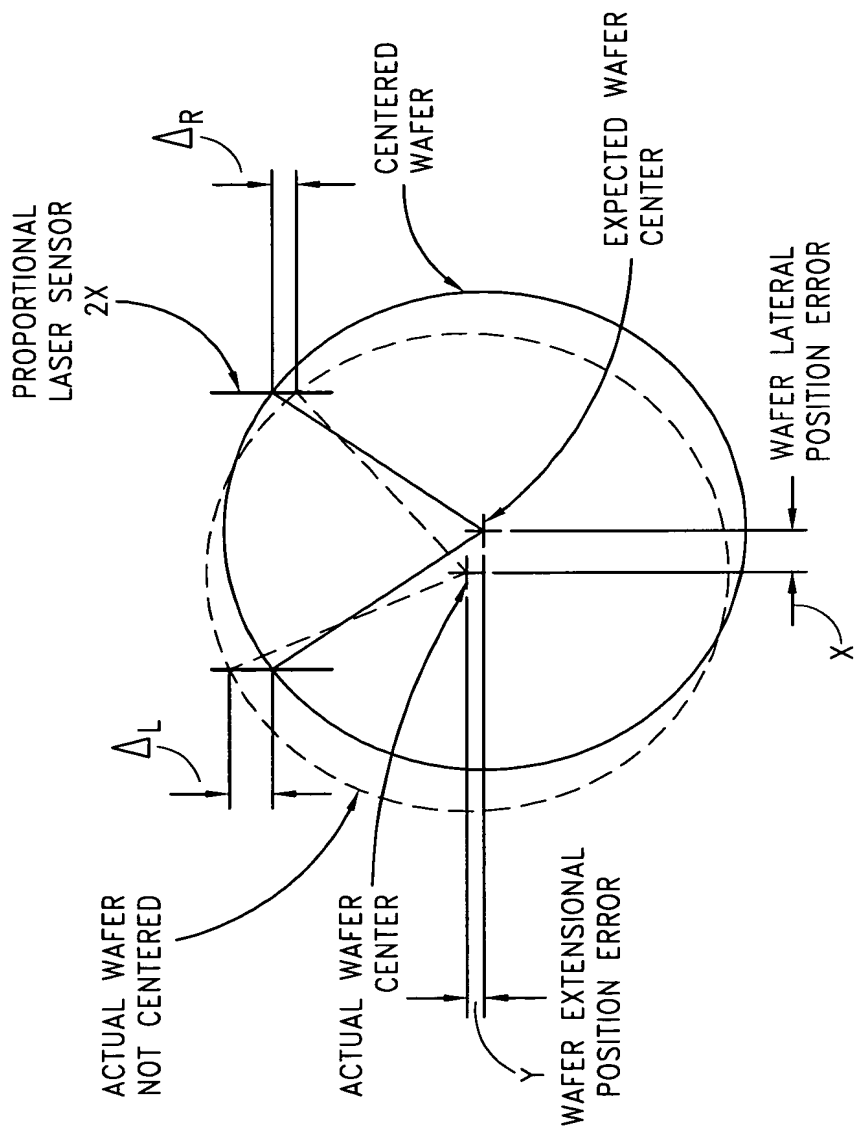


FIG. 12